

IN THE CLAIMS

Please amend the claims as follows:

Claim 1 (Currently Amended): A wafer processing apparatus for processing a wafer transferred from a clean box including an access opening to allow for accessing an inside of the clean box and a lid to close the access opening, wherein the inside of the clean box is separated from a circumstance of the outside of the clean box by closing the access opening with a lid, said wafer processing apparatus comprising:

a chamber;

a first opening formed on a wall of said chamber, said first opening allowing for accessing the inside of the clean box when the clean box is placed beside the chamber so that the access opening confronts said first opening; and

a door member capable of holding the lid of the clean box so as to open or close the access opening and said first opening from an inside of said chamber, said door member having ~~[[an]]~~ a first edge portion and ~~another~~ a second edge portion,

wherein in a condition where said door member closes said first opening, the first edge portion ~~contacts an inside wall of said chamber to overlap a peripheral portion~~ overlaps a part of an inside wall of said chamber at a periphery of said first opening to contact the inside wall of said chamber and the second edge portion does not overlap an inside wall of said chamber at the periphery of said first opening, and

wherein the second ~~said another~~ edge portion forms an aperture defined by an edge portion of said first opening in which the second edge portion does not overlap the inside wall of said chamber at the periphery ~~an edge~~ of said first opening and ~~said another~~ the second edge portion of said door member, ~~the inside of said chamber gas-fluidically communicating with the outside of said chamber through~~ the aperture allowing a gas-fluidic communication

between the inside of said chamber and the outside of said chamber in the condition where said door member closes said first opening.

Claim 2 (Currently Amended): A wafer processing apparatus according to claim 1, wherein the first edge portion is a projection provided at each corner of ~~[[the]]~~ said door ~~[[body]]~~ member.

Claims 3-4 (Canceled).

Claim 5 (Currently Amended): A wafer processing apparatus according to claim 2, wherein the projection protrudes toward the outside of ~~[[the]]~~ said door member.

Claim 6 (Canceled).

Claim 7 (Currently Amended): A wafer processing apparatus according to claim 1: wherein comparing to a case where said door member does not have a projection, the aperture effects suppressing an influence on a gas flow passing through a communication path from the inside to the outside of the chamber ~~in a case of comparing a case that there is no projection.~~

Claim 8 (Currently Amended): A wafer processing apparatus according to claim 7, wherein the influence ~~[[is]]~~ includes a gas flow turbulence generated when ~~[[the]]~~ said door member opens or closes.

Claims 9-10 (Canceled).

Claim 11 (Currently Amended): A wafer processing apparatus for processing a wafer transferred from a clean box including an access opening to allow for accessing an inside of the clean box and a lid to close the access opening, wherein the inside of the clean box is separated from a circumstance of the outside of the clean box by closing the access opening with a lid, said wafer processing apparatus comprising:

a chamber;

a first opening formed on a wall of said chamber, said first opening allowing for accessing the inside of the clean box when the clean box is placed beside the chamber so that the access opening confronts said first opening; and

a door member capable of holding the lid of the clean box so as to open or close the access opening and said first opening from an inside of said chamber,

wherein an outer shape of said door member is larger than a periphery of said first opening to cover a whole part of said first opening from the inside of said chamber, said door member has an aperture within an area in the outer shape of said door member;

and wherein in a condition where said door member closes said first opening, ~~said door member has a through~~ the aperture to gas-fluidically communicate keeps a gas-fluidic communication between the inside and the outside of said chamber ~~through the aperture within an area in the outer shape of said door member.~~